OPTICS & PHOTONICS
International Congress
OPIC 2026

Pacifico Yokohama
Yokohama, Japan
20–24 April 2026

Optical Technology and Measurement for Industrial Applications Conference (OPTM2026)

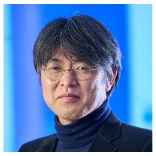
Organizing Committee Chair : **Ryoichi Kuwano,** Hiroshima Institute of Technology (Japan);
Program Committee Chair : **Shin Usuki,** Shizuoka University (Japan);
Program Committee : **Kosuke Asano,** Canon Inc. (Japan); **Prathan Buranasiri,** King Mongkut's Institute of Technology Ladkrabang (Thailand); **Jürgen W. Czarske,** TU Dresden (Germany); **Mizue Ebisawa,** Tokyo Metropolitan Industrial Technology Research Institute (Japan); **Motoharu Fujigaki,** Univ. of Fukui (Japan); **Amalia Martínez-García,** Centro de Investigaciones en Óptica, A.C. (Mexico); **Nathan Hagen,** Utsunomiya Univ. (Japan); **Sen Han,** Univ. of Shanghai for Science and Technology (China); **Feng-Lei Hong,** Yokohama National Univ. (Japan); **Hideki Ina,** Kowa Optronics Co., Ltd., (Japan); **So Ito,** Toyama Prefectural Univ. (Japan); **Lianhua Jin,** Univ. of Yamanashi (Japan); **Yusuke Kajihara,** Institute of Industrial Science, The Univ. of Tokyo (Japan); **Qian Kemao,** NTU (Singapore); **Daesuk Kim,** Chonbuk National Univ. (Korea); **Jonathan D. Kofman,** Univ. of Waterloo (Canada); **Daisuke Kono,** Kyoto Univ. (Japan); **Yu-Lung Lo,** National Cheng Kung Univ. (Taiwan); **Hiraku Matsukuma,** Tohoku Univ. (Japan); **Kimihisa Matsumoto,** Toyama Prefectural Univ. (Japan); **Masaki Michihata,** The Univ. of Tokyo (Japan); **Jessica Onaka,** Utsunomiya Univ. (Japan); **Yukitoshi Otani,** Utsunomiya Univ. (Japan); **Pavel Pavlicek,** Palacký Univ. Olomouc (Czech Republic); **Ryo Sato,** Tohoku Univ. (Japan); **Satoru Takahashi,** The Univ. of Tokyo (Japan); **Tsutomu Uenohara,** The Univ. of Osaka (Japan); **Toshitaka Wakayama,** Saitama Medical Univ. (Japan); **Wei-Chung Wang,** National Tsing Hua Univ. (Taiwan); **Gao Wei,** Tohoku Univ. (Japan) ; **Jiangtao Xi,** Univ. of Wollongong (Australia); **Toru Yoshizawa,** NPO 3D Associates (Japan); **Song Zhang,** Purdue Univ. (United States);

CONFERENCE CHAIRS

Rainer Tutsch
Technische Univ.
Braunschweig
(Germany)

Nathan Hagen
Utsunomiya Univ.
(Japan)

Mariko Kajima
National Institute of
Advanced Industrial
Science and
Technology
(Japan)



Yasuhiro Mizutani
The Univ. of Osaka
(Japan)

Papers on the following and related topics are solicited for this conference:

- 3D profilometry
- polarimetry/ellipsometry
- novel optical testing
- surface inspection methods and applications
- absolute testing for metrology
- application of interferometric techniques
- machine/robot vision methods, architectures and applications
- lighting methods and systems for inspection
- dynamic measurement
- unique optical systems for inspection and measurements
- 2D and 3D machine vision methods and applications
- 3D data acquisition
- freeform testing
- scatterometry
- unconventional microscope for inspection
- super-high accurate measurement for smooth surfaces
- micro- and nano-scale measurement methods
- structured light methods, fringe projection measurement and applications
- phase shifting methods applied to industrial inspection
- mechanic-optics and photonics for metrologyand inspection
- optical inspection by optical comb
- super resolution microscope for inspection
- spherical and aspherical measurements
- color metrology of manufactured goods
- on-line and process control measurements
- on-machine tool measurements of shape and finish
- high-resolution and high-speed inspection applications
- novel interferometry.

Submit your abstract today
https://opicon.jp/conferences/OPTM
Submission Deadline: 22 December 2025

◎**Conference dinner of OPTM 2026** **is tentatively scheduled as follows**:

Dinner cruise of OPTM2026: Tuesday 21 April 2026 17:30～20:00 (at Yokohama bay from near the convention center)